



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of

COOPER et al.

Atty. Ref.: 2476-30

Serial No. 10/603,092

TC/A.U.: 2851

Filed: June 25, 2003

Examiner:

For: PROGRAMMABLE PHOTOLITHOGRAPHIC MASK SYSTEM AND  
METHOD

\* \* \* \* \*

February 19, 2004

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

**INFORMATION DISCLOSURE STATEMENT**

In accordance with Rule 97, the undersigned attorney submits the documents listed on the attached form PTO-1449. A copy of each document is enclosed.

The Examiner is requested to initial the attached form PTO-1449 and to return a copy to the undersigned as an indication that the attached documents have been considered and made of record in this case.

Respectfully submitted,

**NIXON & VANDERHYE P.C.**

By:

Robert W. Faris

Reg. No. 31,352

RWF:ejs

1100 North Glebe Road, 8th Floor

Arlington, VA 22201-4714

Telephone: (703) 816-4000

Facsimile: (703) 816-4100

**INFORMATION DISCLOSURE  
CITATION**

Atty. Docket No.

Serial No.

2476-30

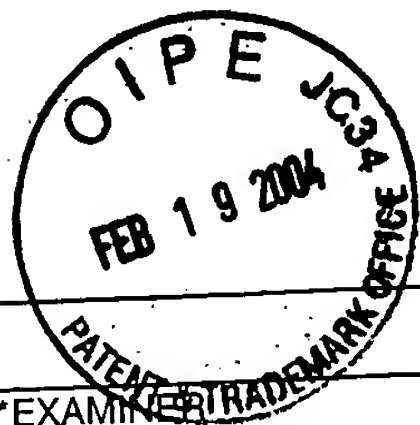
to be assigned

COOPER et al.

Filing Date

Group

Concurrently Herewith



**U.S. PATENT DOCUMENTS**

[illegible]

\*Examiner

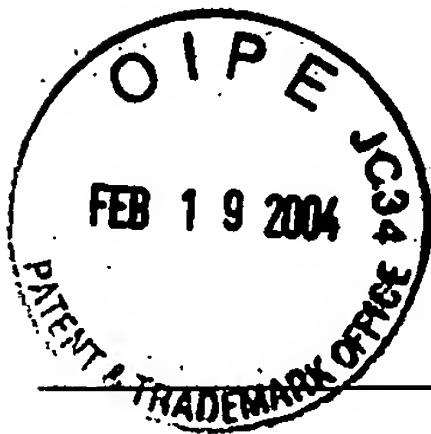
Date Considered \_\_\_\_\_

*Examiner	Date Considered
<p>Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application.</p>	

Form PTO-FB-A820 (Also PTO-14)

Form PTO-FB-A820 (Also PTO-1449)

## INFORMATION DISCLOSURE CITATION



Atty. Docket No.

Serial No.

2476-30

to be assigned

Applicant

COOPER et al.

Filing Date

Group

Concurrently Herewith

## FOREIGN PATENT DOCUMENTS

[illegible]

**OTHER DOCUMENTS (including Author, Title, Date, Pertinent pages, etc.)**

	Yu and Cardona, <i>Fundamentals of Semiconductors: Physics and Material Properties</i> (1999) at page 196
	Tutorial at <a href="http://plc.cwru.edu/tutorial/enhanced/files/lcd/tn/tn.htm">http://plc.cwru.edu/tutorial/enhanced/files/lcd/tn/tn.htm</a> .
	IBM Technical Disclosure Bulletin, Vol. 34 No. 10A, "Ultra-Resolution Image Transfer," (March 1992)
	Paufler et al., "High-throughput optical direct write lithography," <i>Solid State Technology</i> , pp. 175, 176, 178, 180, 182 (June 1997)
	Kuwamura et al., "Analysis of Operating Mechanism in Semiconductor Optical Modulator with Electron-Depleting Adsorption Control," <i>Electronics and Communications in Japan</i> , Pt. 2, Vol. 79, No. 5, pp. 616-625 (1996)
	Kuwamura et al., "Design and Fabrication of a Surface-Illuminated-Type Semiconductor Optical Modulator With Electron-Depleting Adsorption Control," <i>Electronics and Communications in Japan</i> , Pt. 2, Vol. 81, No. 11, pp. 55-56 (1998)
	Yamada et al., "A Semiconductor Optical Switch Utilizing Optical Absorption in Depletion Layer," <i>CLEO</i> 1991, page 158
	Kuwamura, et al.; "Panel-Type Semiconductor Optical Modulator Using Electron Depleting Absorption Control," <i>Jpn. J. Appl. Phys.</i> Vol. 32 (1993), pp. 578-582, Part 1, No. 1B (January 1993)
	Binet et al., "Electric field effects on excitons in gallium nitride," <i>PHYSICAL REVIEW B</i> , Vol. 54, Number 11 (9/15/1996).

**\*Examiner**

Date Considered \_\_\_\_\_

Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to application.